

분과초청 3

ION BEAM RESEARCH IN SIM

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The development of ion beam technique and its application in SIM (Shanghai Institute of Metallurgy) are briefly reviewed. Results of film synthesis by ion beam enhanced deposition and material surface modification by ion implantation are reported. In addition, the industrial applications are discussed.

The contents of the report are arranged as follows:

(1) Materials synthesis by Ion Beam

Films formation by ion beam enhanced deposition

Synthesis of multi-layer structure by ion beam technique

(2) Surface modification by ion implantation

Implantation in silicon

Ion bombardment effects in porous silicon

Effects of ion implantation in intermetallic compounds

(3) Application of ion beam technique